

# VAKSiS

R&D AND ENGINEERING

MIDAS® Twin



## PRODUCT INFORMATION

MIDAS Twin series is a member of Vaksis MIDAS COATING SYSTEMS platforms comprised of two chambers with a common pumping station. The series are composed of prismatic vacuum chambers and involve the techniques and combinations below:

## CONFIGURATION MATRIX

Techniques	Magnetron Sputtering (MS)	Thermal Evaporation (Th E)	Electron Beam (e-Beam)	Organic and Metal Evaporation (OLED/OPV)	Multi Tech.
MIDAS Twin	✓	✓	✓	✓	MS, Th E, e-Beam, OLED/OPV

## TECHNICAL SPECIFICATIONS

Ultimate Vacuum Pressure .....  $\leq 5 \times 10^{-8}$  Torr  
Number of Chambers ..... 2  
Substrate Size ..... 4"- 8" diameter  
Substrate Heating ..... max. 800°C  
Substrate Rotation ..... 3-30 rpm  
Cooling..... Where necessary  
Deposition Mode ..... Upward  
Load Lock Chamber ..... Optional  
Control ..... Fully Automatic

## POWER SOURCES

- DC and/or RF Power Supply for Sputtering Magnetron Source
- Effusion Cell A.C. Power Supply for Metal and/or Organic Evaporation Sources
- High-Current Low-Voltage A.C. Power Supply for Resistive Thermal Evaporation Source
- Power Supply for Electron Beam Evaporation Source

## SOFTWARE

System operation by user-friendly software. It is not only the automation and control software but also coating management software which allows the user design his/her specific coating experiments, examine the process parameters used in the past, and use the recipes/coatings developed in the past without hustle.

Human and machine safeties are prime importance in the operations performed by the software. A graphical user interface will allow the user to see the status of the system during operation.